

## **Supporting Information:**

### **Supersensitive All-Fabric Pressure Sensors Using Printed Textile**

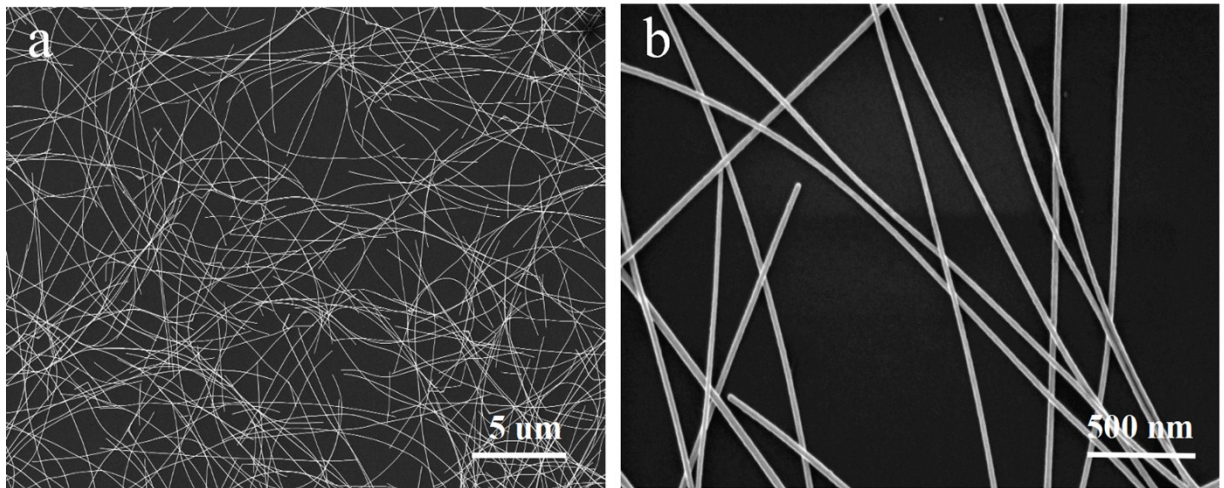
### **Electrode Arrays for Human Motion Monitoring and Human-**

### **Machine Interaction**

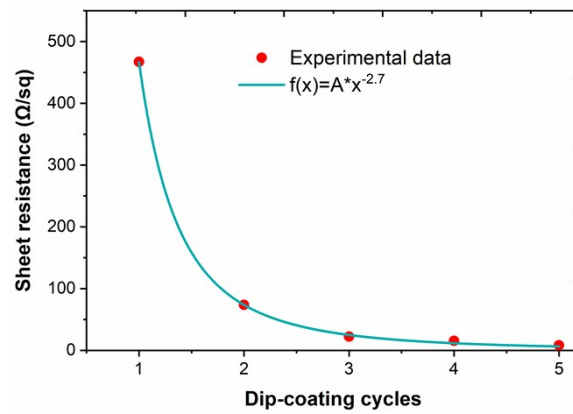
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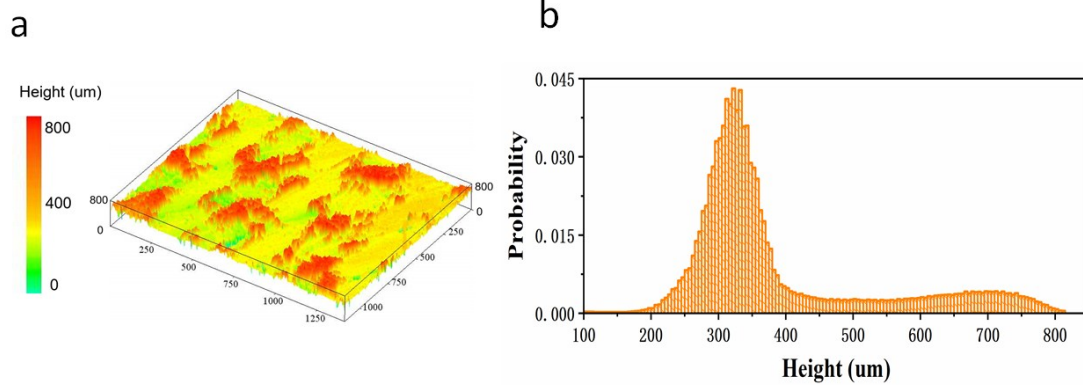
<sup>b</sup>Research Institute for New Materials Technology, Chongqing University of arts and sciences, Chongqing 402160, China.

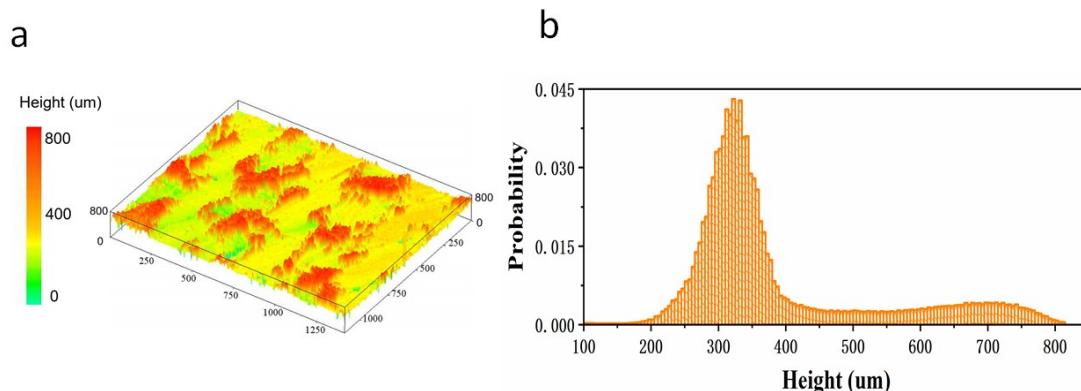


**Fig. S1.** SEM images of AgNWs with different magnifications (a,b).

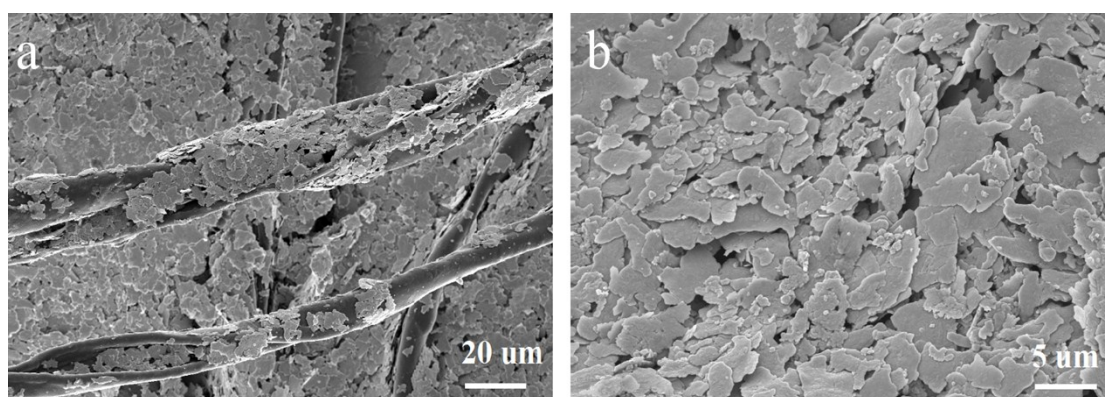


**Fig. S2.** The sheet resistance of AgNWs-decorated cotton with different dip-coating cycles.

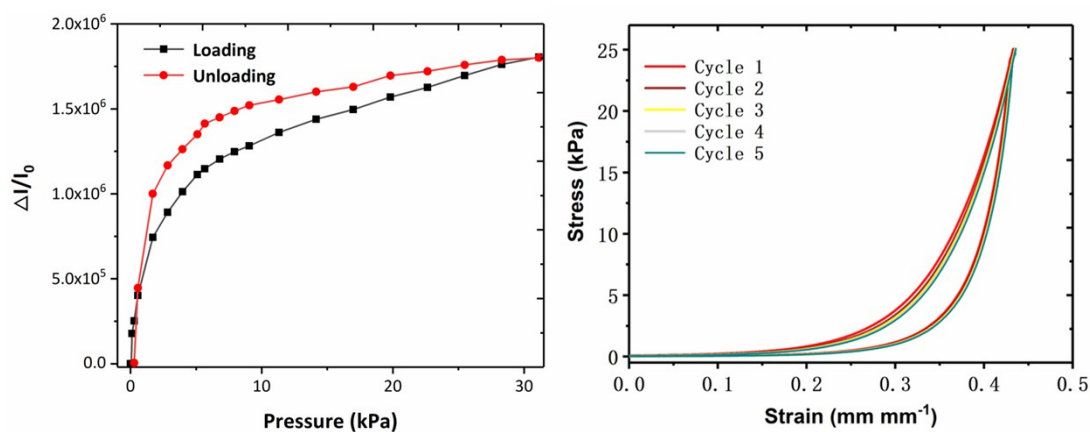




**Fig. S4.** (a) 3D morphology of the AgNWs-coated cotton. (b) The height distribution of the rough surface.

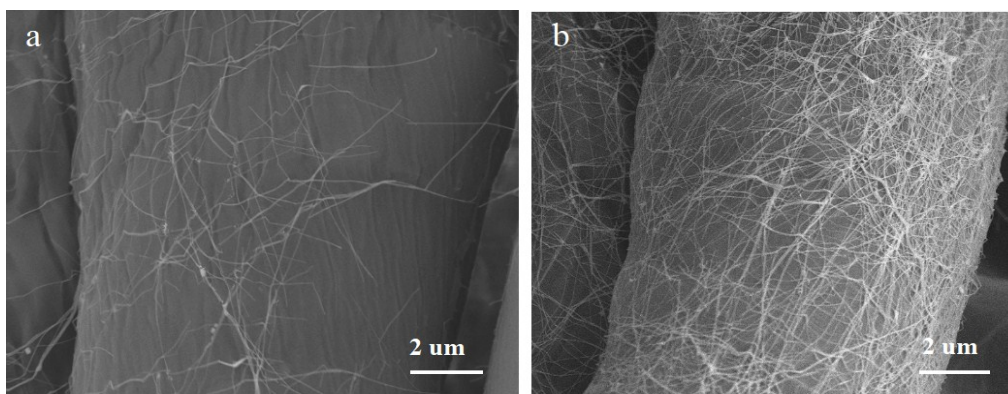


**Fig. S5.** (a, b) SEM images of Ag-coated on cotton substrate with different magnifications.

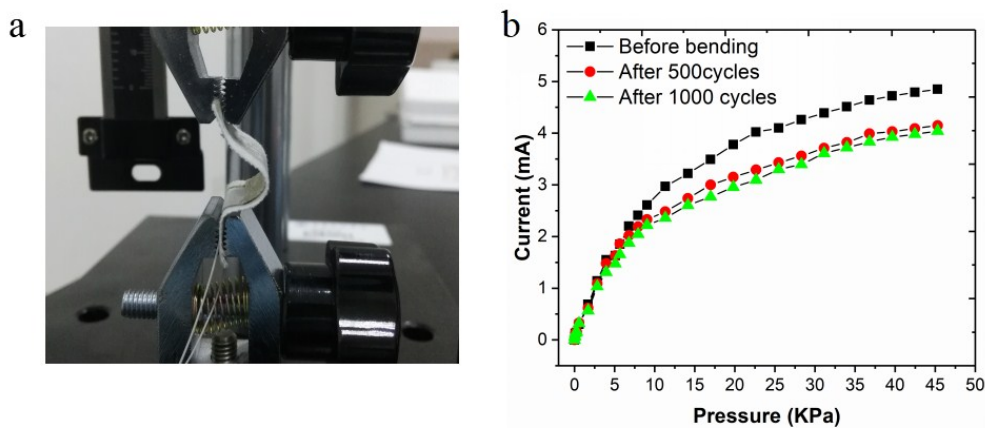


**Fig. S6** (a) Loading-unloading transfer curves of our pressure sensor. (b) Five consecutive compression tests on the AgNWs-coated cotton.

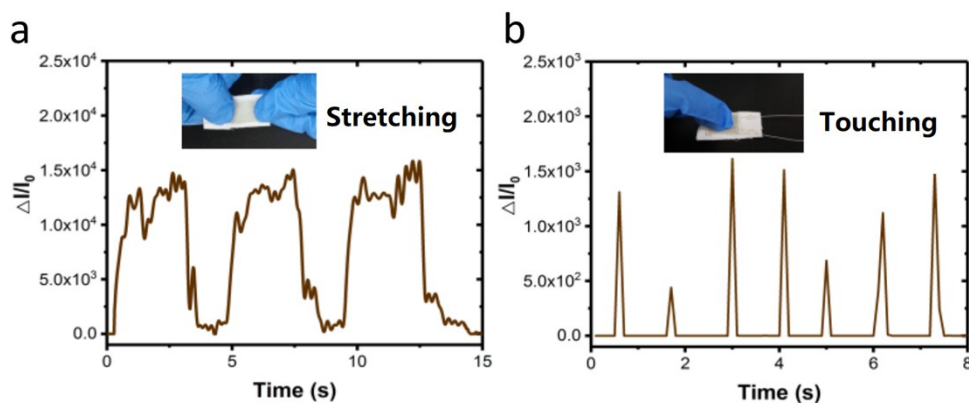
To assess the mechanical properties of the conductive fabric, we measured the compressive stress as a function of strain. An effective elastic modulus ( $E_{\text{eff}}$ ) was defined as the slope of the stress values strain plot, and the AgNWs-decorated cotton showed a very low  $E_{\text{eff}}$  at a low-pressure regime and subsequently increased with compression. The  $E_{\text{eff}}$  at 5 kPa was 85.82 kPa, which is lower than the typical low-modulus elastomer previously reported, such as PDMS and PPy hydrogels (about 200 kPa)<sup>[4]</sup>.



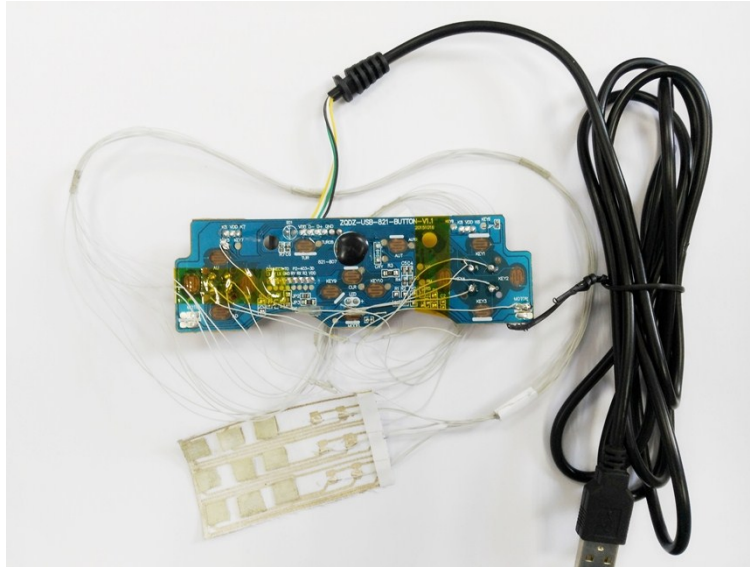
**Fig. S7** (a) SEM of AgNWs-coated fiber with 1 dip-coating cycle. (b) SEM of AgNWs-coated fiber with 5 dip-coating cycles.



**Fig. S8.** (a) The photograph of the bent device. (b) The performance of the pressure sensor after 1000 bending cycles.



**Fig. S9.** Digital photographs and current signal responding to mechanical stimulus for several loading/unloading cycles: (a) stretching, (b) touching.



**Fig. S10.** Digital photograph of the hardware of human-computer interactive system.

**Video S1:** Sensing arrays used for human-machine interaction to play the piano.

**Video S2:** Sensing arrays used for human-machine interaction to play computer games.

**Table S1.** Comparison of the sensitivity, detection limit, response time and power assumption of our device with those in the literature.

Device type	Materials	Switching ratio	Sensitivity ( kPa <sup>-1</sup> )	Detection limit	Response/relaxation time ( ms )	Operating voltage (V)	Ref.
Resistive	Textile/AgNWs/Silver paste	~10 <sup>6</sup> (3 kPa)	~5.65*10 <sup>5</sup>	0.34 Pa	6/13	0.1	<b>This work</b>
Resistive	Textile/CNTs/Ni	100 (10 kPa)	14.4	2 Pa	18/24	<6	1
Resistive	Textile/AgNWs/rGo	~3.4 (3 kPa)	5.8	0.125 Pa	29.5/15.6	-	2
Resistive	PDMS/AgNWs /Conductive threads	~10 <sup>7</sup> (3 kPa)	1.04×10 <sup>4</sup> - 6.57×10 <sup>6</sup>	0.6 Pa	4/14	0.1	3
Resistive	PET/PPy hydrogel	~10 <sup>3</sup> (5 kPa)	<133.1	0.8 Pa	47/-	-	4
Resistive	PI/Carbon-decorated fabric	~4 (10 kPa)	0.585	-	4/4	-	5
Resistive	PDMS/AuNWs-coated paper	~3.5 (3 kPa)	1.14	13 Pa	17/-	1.5	6
Resistive	PDMS/PEDOT:PSS/ PUD	~20 (4 kPa)	10.32	23 Pa	200/-	0.2	7
Resistive	PU fiber/AgNWs	~1.1 (5 kPa)	0.12	10 mg	35/15	-	8
Resistive	Cu/PAAM hydrogel	~1.5 (8 kPa)	0.35	100 Pa	-	-	9
Resistive	PDMS/SWNTs	~1.3 (1 kPa)	1.8	0.6	<10/-	2	10
Resistive	Au/PDMS/CNT/ITO/ PET/AgNWs	~500 (3 kPa)	204.4	0.2	<70/-	-	11
Resistive	PDMS/ZnO NWs	~5 (5 kPa)	6.8	0.6	<5/-	-	12
Capacitance	Textile fiber/Rubber/ AgNP	~1.5 (5 kPa)	0.210	8mg	40/10	1	13
Capacitance	PDMS/Ecoflex/CNTs	~1.025 (10 kPa)	0.034-0.05	0.38 Pa	63/-	-	14
Capacitance	PDMS/AgNWs	~2 (1 MPa)	0.00162	~2.7 g	40/-	-	15
Triboelectricity	PET/PDMS/EVA	-	0.006	1000 Pa	70/-	-	16
Piezoelectricity	PET/ZnO NWs	-	0.131	3500	150/-	1	17
Piezoelectricity	Au/ITO/ZnO	-	1.64	-	-	0.2	18

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